

(S3.2) updating Θ with a value computed by $\Theta + \max\{\Delta_1, \Delta_2, \dots, \Delta_{|k|}\}$; and

(S3.3) finding the part of the schedule for ST_k by recomputing the robot waiting times with the updated cycle time Θ ;

where:

$EST_{k,q}$ or $ST_{k,q}$ is the EST or the ST having the single-cluster tool C_i and a branch thereof, $B_{i,q}$.

3. The method of claim 1, further comprising:

identifying, in the treelike hybrid K-cluster tool, ST_j with $j = \max_{i \in F} \{1\}$, and one or more ESTs of ST_j , the one or more ESTs being denoted as EST_{j-1} , EST_{j-2} down to EST_i such that an upstream adjacent tool of C_i is a fork tool;

determining a first part of the schedule for ST_j by performing the generating algorithm;

determining a second part of the schedule for EST_{j-1} based on the first part of the schedule;

repeating determining one part of the schedule EST_{j-m} based on a determined part of the schedule for EST_{j-m+1} until the one or more ESTs are scheduled.

4. The method of claim 2, further comprising:

identifying, in the treelike hybrid K-cluster tool, ST_j with $j = \max_{i \in F} \{1\}$, and one or more ESTs of ST_j , the one or more ESTs being denoted as EST_{j-1} , EST_{j-2} down to EST_i such that an upstream adjacent tool of C_i is a fork tool;

determining a first part of the schedule for ST_j by performing the generating algorithm;

determining a second part of the schedule for EST_{j-1} based on the first part of the schedule; and

repeating determining one part of the schedule EST_{j-m} based on a determined part of the schedule for EST_{j-m+1} until the one or more ESTs are scheduled.

5. The method of claim 1, wherein R_k is single-arm or double-arm.

6. The method of claim 2, wherein R_k is single-arm or double-arm.

7. A treelike hybrid K-cluster tool having K single-cluster tools each having a robot for wafer handling, wherein the treelike hybrid K-cluster tool further comprises one or more processors configured to execute a process of generating a one-wafer cyclic schedule according to the method of claim 1.

8. A treelike hybrid K-cluster tool having K single-cluster tools each having a robot for wafer handling, wherein the treelike hybrid K-cluster tool further comprises one or more processors configured to execute a process of generating a one-wafer cyclic schedule according to the method of claim 2.

9. A treelike hybrid K-cluster tool having K single-cluster tools each having a robot for wafer handling, wherein the treelike hybrid K-cluster tool further comprises one or more processors configured to execute a process of generating a one-wafer cyclic schedule according to the method of claim 3.

10. A treelike hybrid K-cluster tool having K single-cluster tools each having a robot for wafer handling, wherein the treelike hybrid K-cluster tool further comprises one or more processors configured to execute a process of generating a one-wafer cyclic schedule according to the method of claim 4.

11. A treelike hybrid K-cluster tool having K single-cluster tools each having a robot for wafer handling, wherein the treelike hybrid K-cluster tool further comprises one or more processors configured to execute a process of generating a one-wafer cyclic schedule according to the method of claim 5.

12. A treelike hybrid K-cluster tool having K single-cluster tools each having a robot for wafer handling, wherein the treelike hybrid K-cluster tool further comprises one or more processors configured to execute a process of generating a one-wafer cyclic schedule according to the method of claim 6.

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